

WHAT IS CLAIMED:

1. A device for holding a template, said device comprising:  
a body having an opening to receive said template; and  
a supporting plate coupled to said body, with said supporting plate being substantially transparent to a curing agent.
2. The device as recited in claim 1 wherein said curing agent comprises ultraviolet radiation.
3. The device as recited in claim 1 wherein said supporting plate is formed from material selected from a set of materials consisting of quartz, sapphire, and silicon dioxide.
4. The device as recited in claim 1 further including a vacuum system in fluid communication with said supporting plate to apply a vacuum to said template.
5. The device as recited in claim 1 further including a vacuum system in fluid communication with said supporting plate to apply a vacuum between said supporting plate and said body.
6. The device as recited in claim 1 wherein said supporting plate is configured to reduce deformation of said template due to forces present during an imprint lithography process.

7. The device as recited in claim 1 further including a reflective element connected to a portion of said body located within said opening.

8. A device for holding a template, said device comprising:

a body having an opening to receive said template; and  
a supporting plate coupled to said body, with said supporting plate substantially transparent to ultraviolet radiation.

9. The device as recited in claim 8 wherein said supporting plate is formed from material selected from a set of materials consisting of quartz, sapphire, and silicon dioxide.

10. The device as recited in claim 181 further including a vacuum system in fluid communication with said supporting plate to apply a vacuum to said template.

11. The device as recited in claim 8 further including a vacuum system in fluid communication with said supporting plate to apply a vacuum between said supporting plate and said body.

12. The device as recited in claim 8 wherein said supporting plate is configured to reduce deformation of said template due to forces present during an imprint lithography process.

13. The device as recited in claim 8 further including a reflective element connected to a portion of said body located within said opening.

14. A device for holding a template, said device comprising:

a body having an opening to receive said template;  
a supporting plate coupled to said body, with said supporting plate substantially transparent to a curing agent; and

a vacuum system in fluid communication with said supporting plate to apply a vacuum between said supporting plate and said body.

15. The device as recited in claim 14 wherein said curing agent comprises ultraviolet radiation.

16. The device as recited in claim 14 wherein said supporting plate is formed from material selected from a set of materials consisting of quartz, sapphire, and silicon dioxide.

17. The device as recited in claim 14 wherein said supporting plate is configured to reduce deformation of said template due to forces present during an imprint lithography process.

18. The device as recited in claim 14 further including a reflective element connected to a portion of said body located within said opening.